

MAY 16 2001

RESPONSE UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE EXAMINING  
GROUP 1763

208544US-2

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
TAKAHIRO HORIGUCHI ET AL : EXAMINER: KACKAR, RAM N.  
SERIAL NO: 09/855,493 :  
FILED: MAY 16, 2001 : GROUP ART UNIT: 1763  
FOR: SINGLE-SUBSTRATE-PROCESSING:  
APPARATUS FOR SEMICONDUCTOR  
PROCESS

AMENDMENT UNDER 37 C.F.R. § 1.116

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

In response to the Office Action dated December 17, 2002, please amend the above-identified patent application as follows:

IN THE CLAIMS

**Please amend the claims to read as shown below:**

21. (Amended) A single-substrate-processing apparatus, comprising:

an airtight process chamber including a casing and configured to process a target

substrate;

a worktable configured to support the target substrate within the casing of the process

chamber.